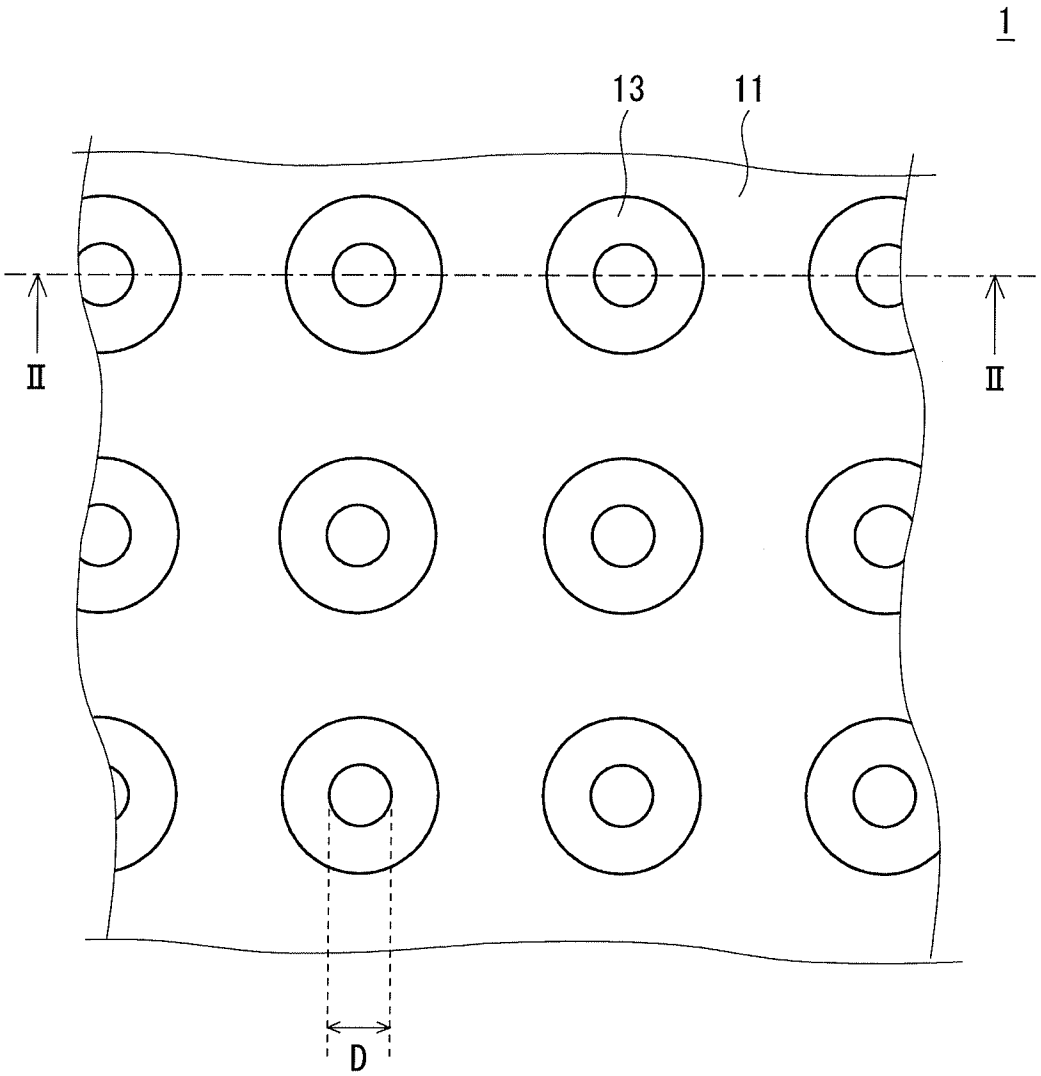


Fig. 1

Fig. 2

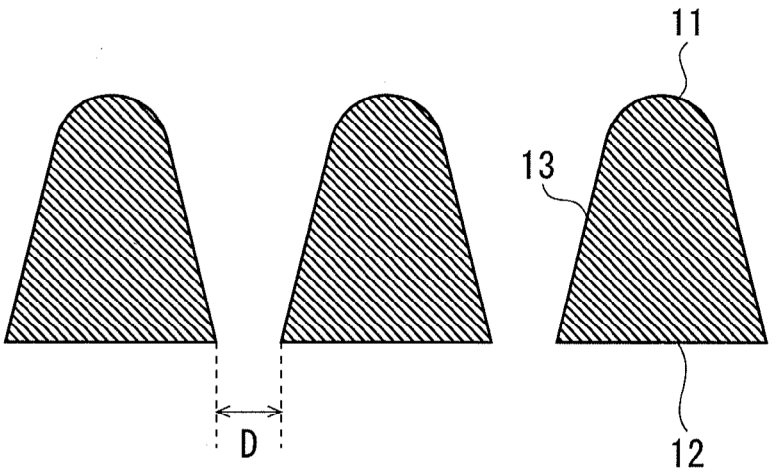
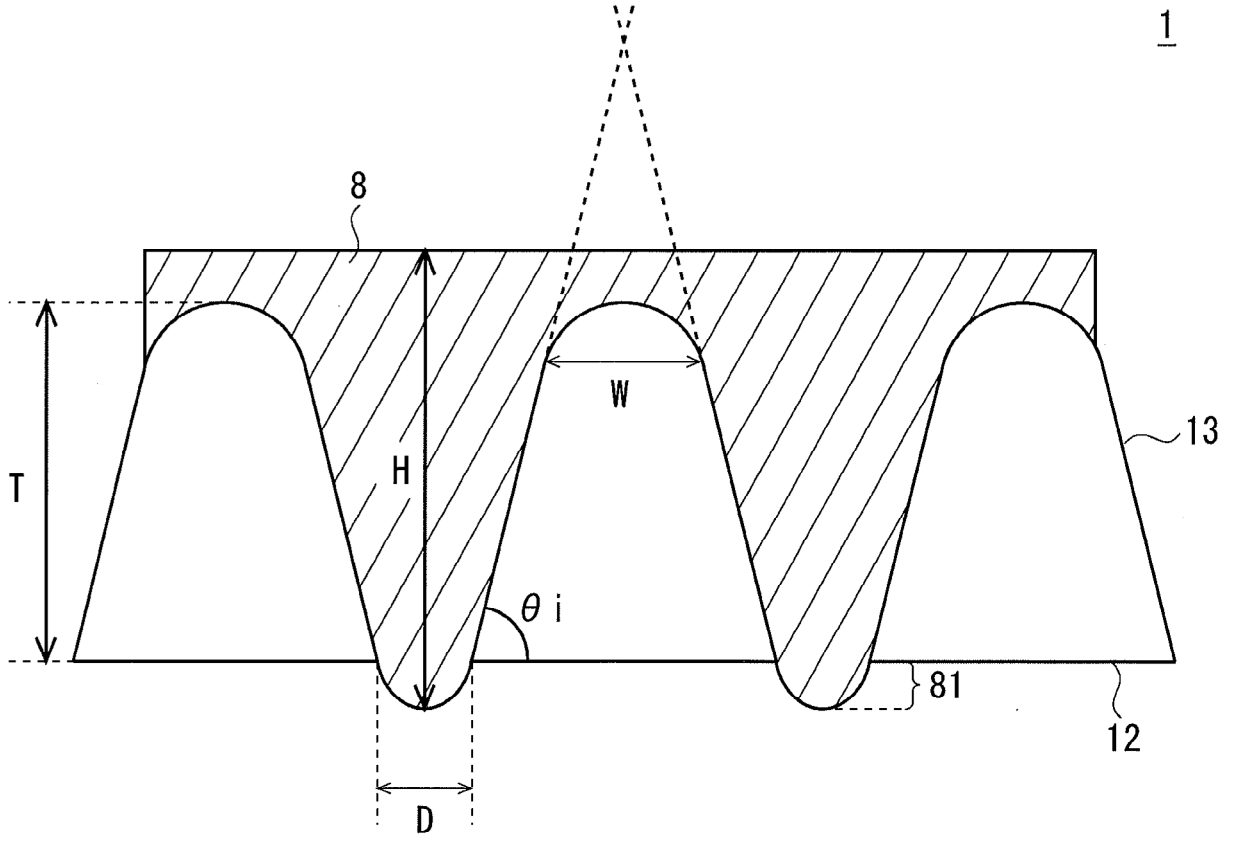


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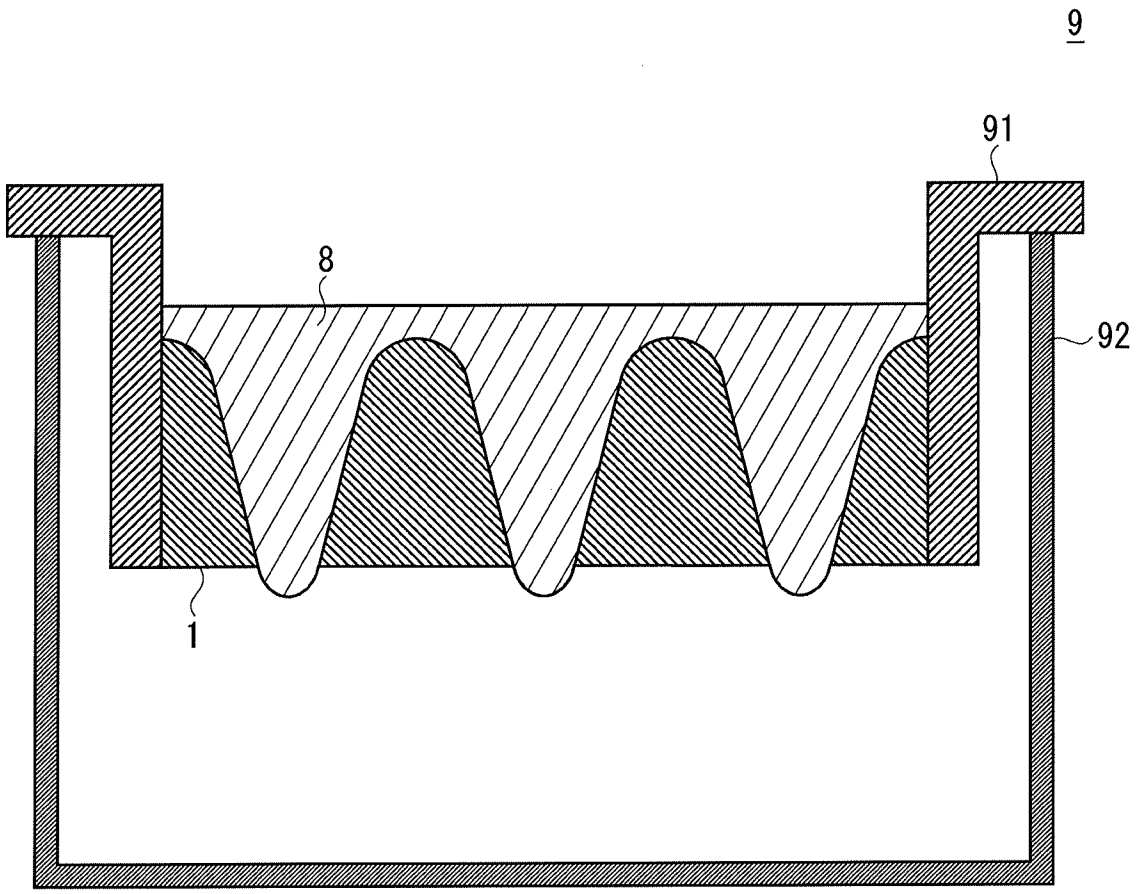


Fig. 4

Fig. 5

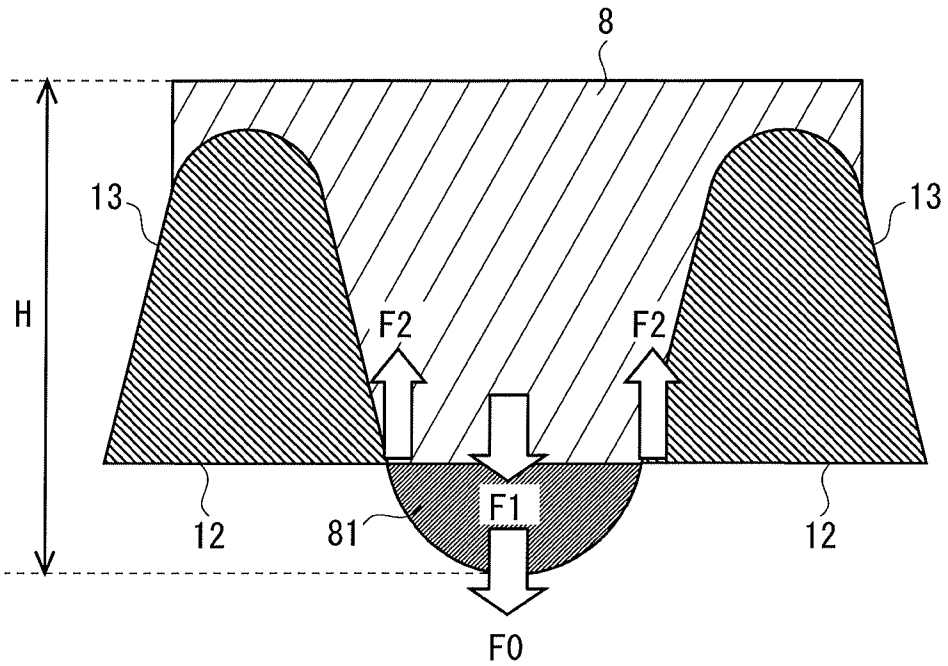

8
13
13
H
F2
F2
F1
12
81
12
F0

Fig. 6

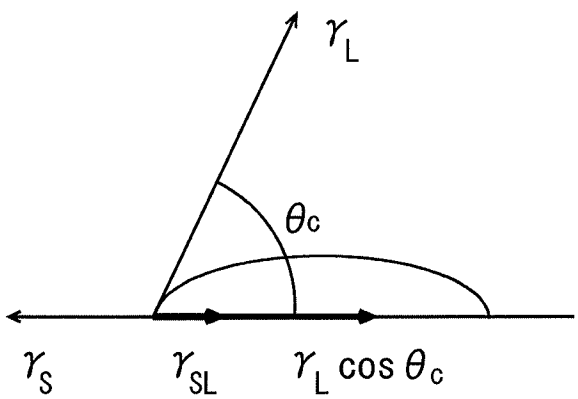

γ_L
θ_c
γ_S
γ_{SL}
$\gamma_L \cos\theta_c$

Fig. 7

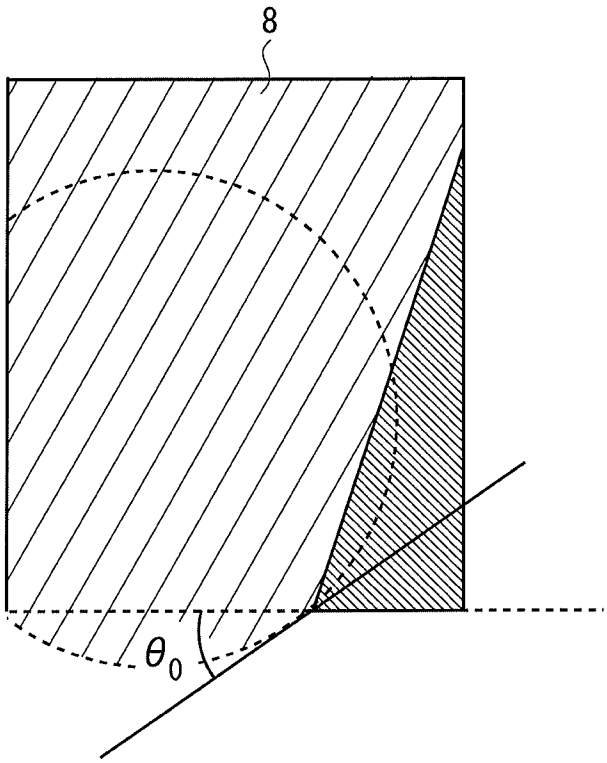

8
θ_0

Fig. 8

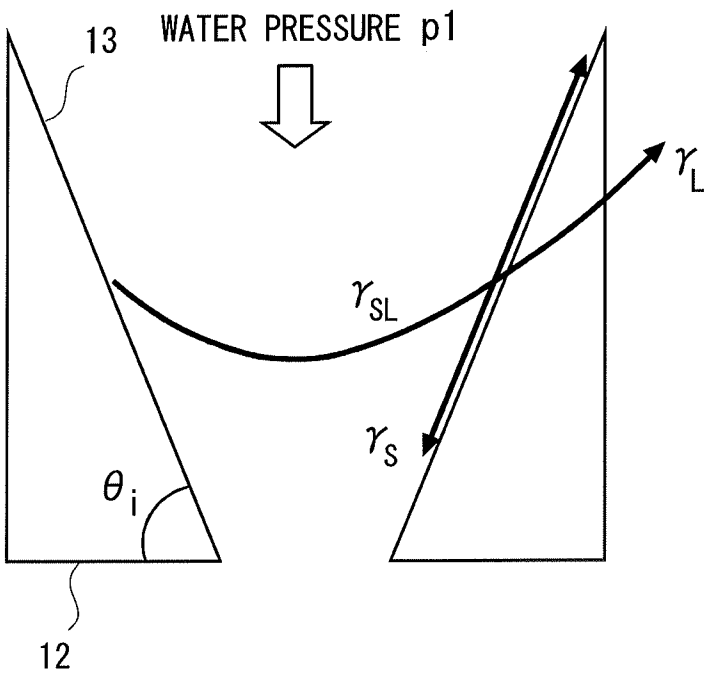

13
WATER PRESSURE p1
γ_L
γ_{SL}
γ_S
θ_i
12

Fig. 9

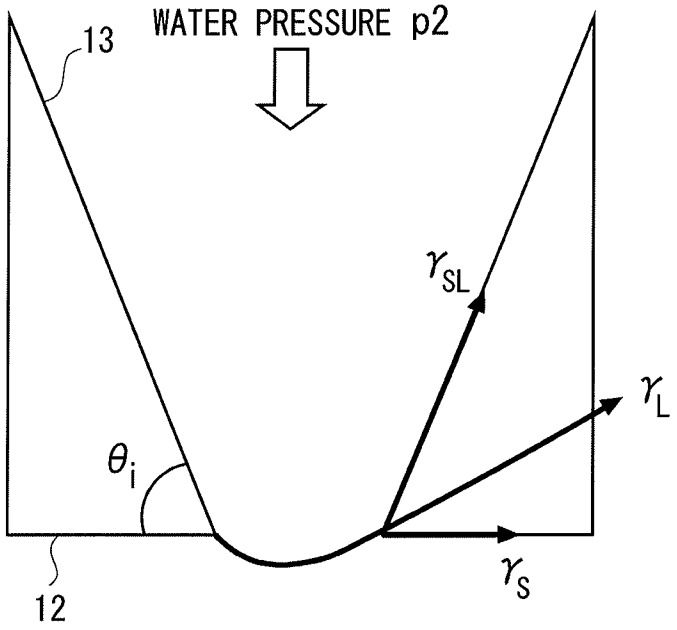
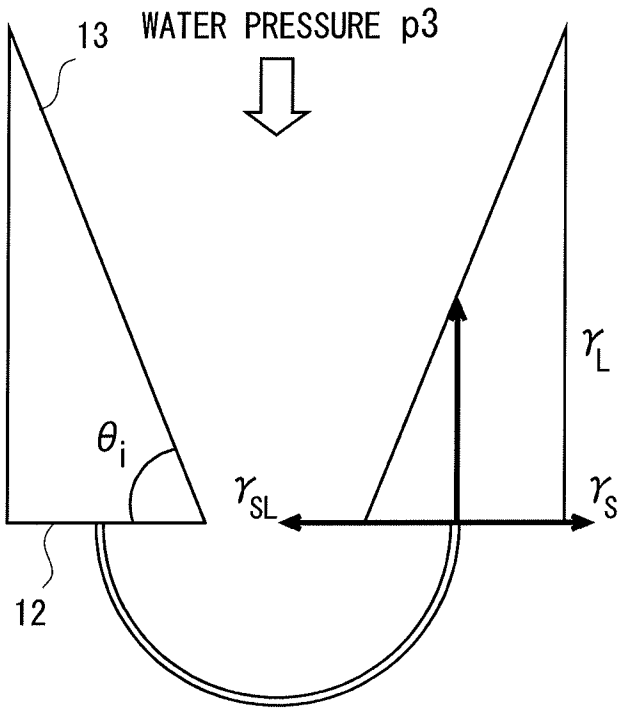

13
WATER PRESSURE p2
γ_{SL}
γ_L
θ_i
γ_S
12

Fig. 10


13
WATER PRESSURE p3
γ_L
θ_i
γ_{SL}
γ_S
12

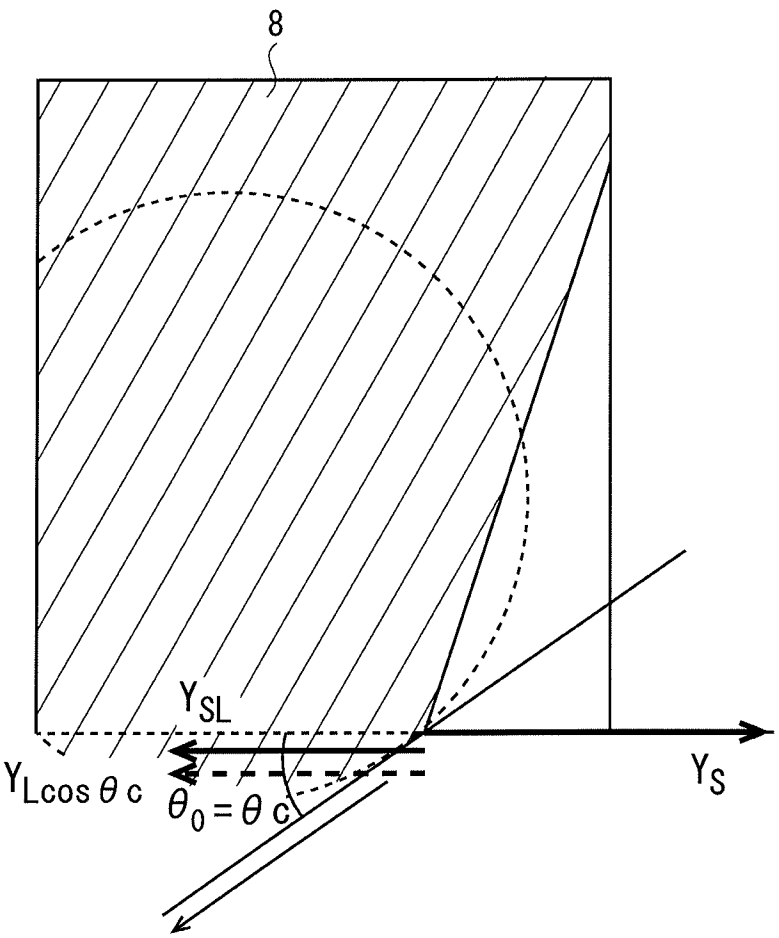
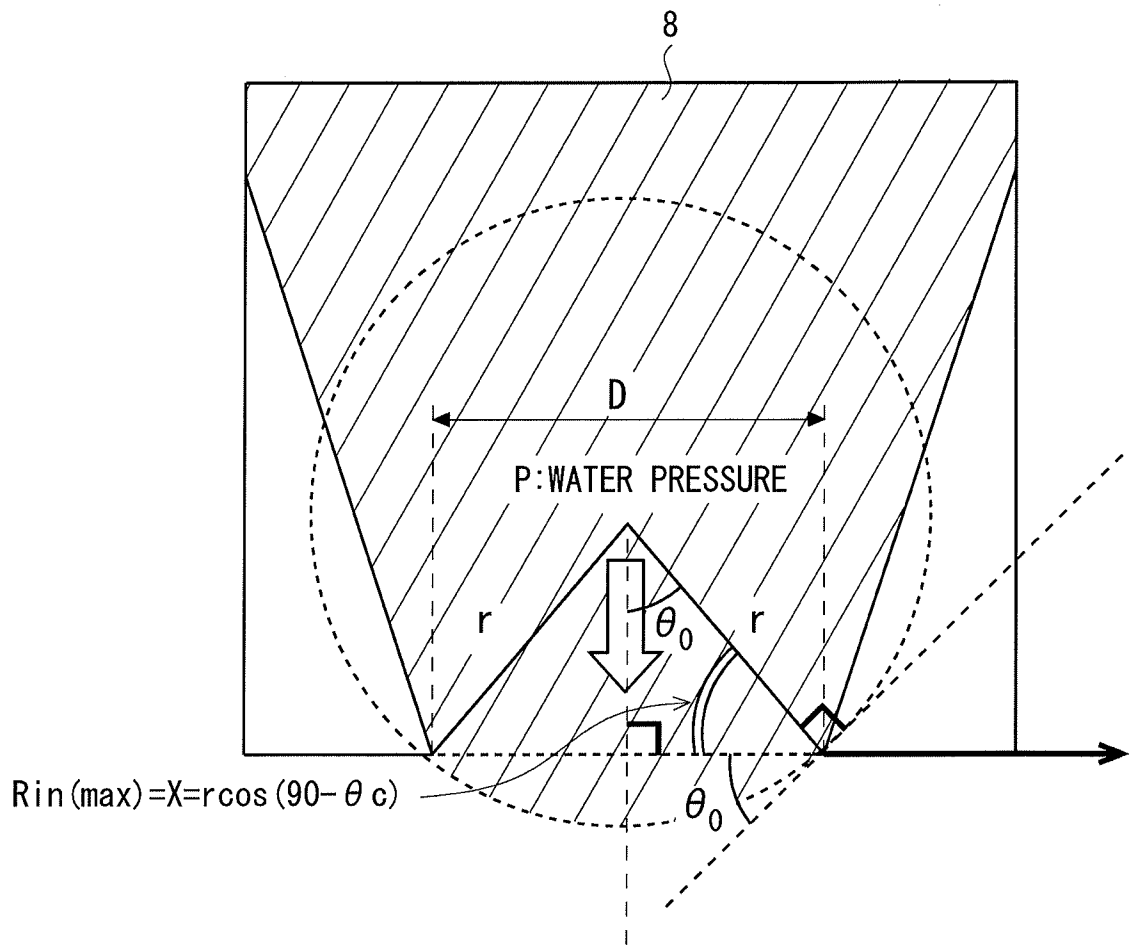


Fig. 11



$\theta 0 = \theta c$

Fig. 12

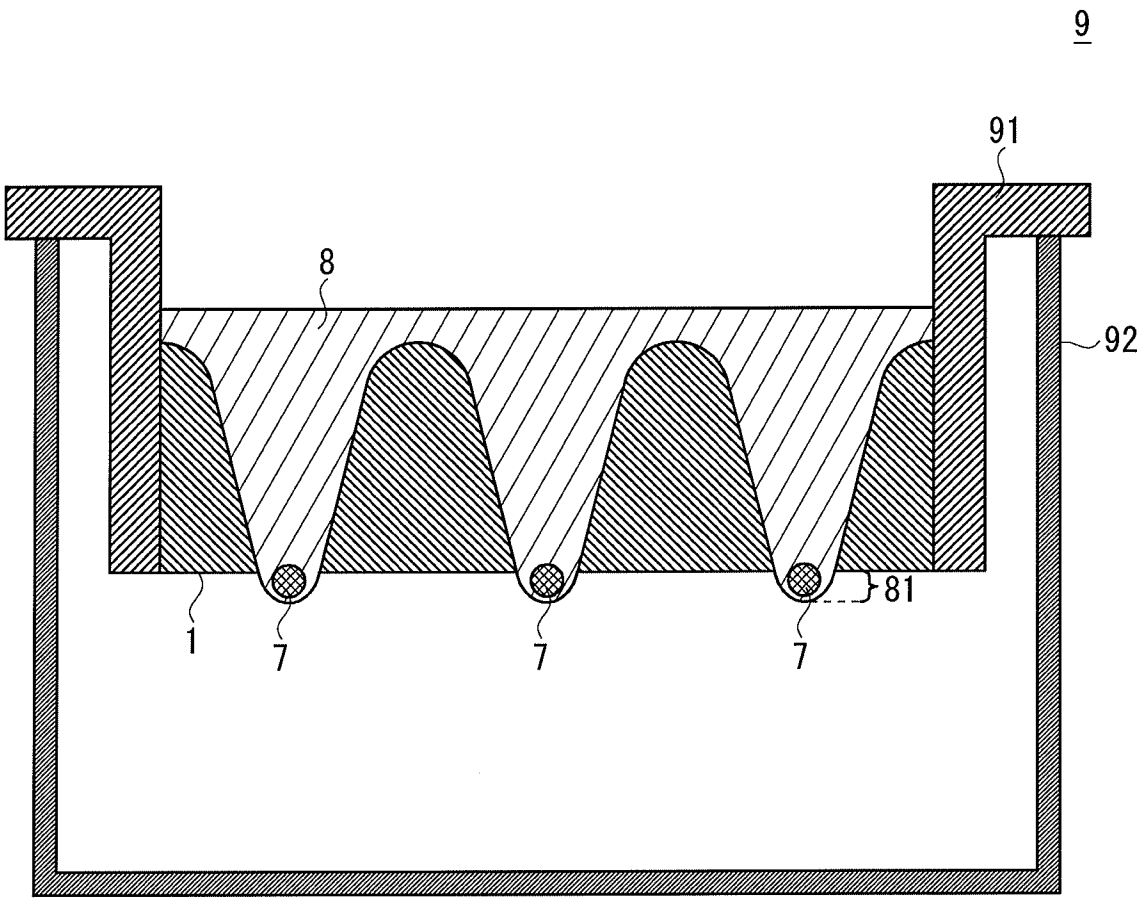


Fig. 13

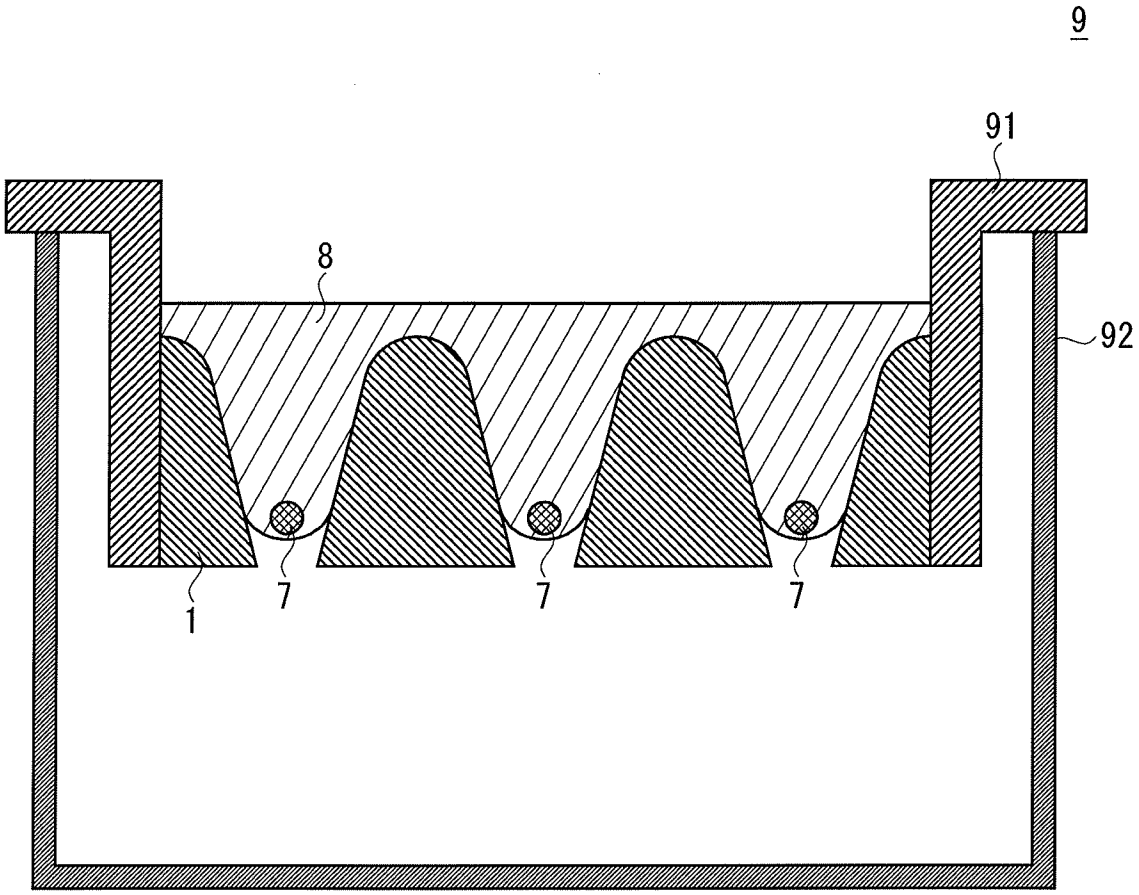


Fig. 14

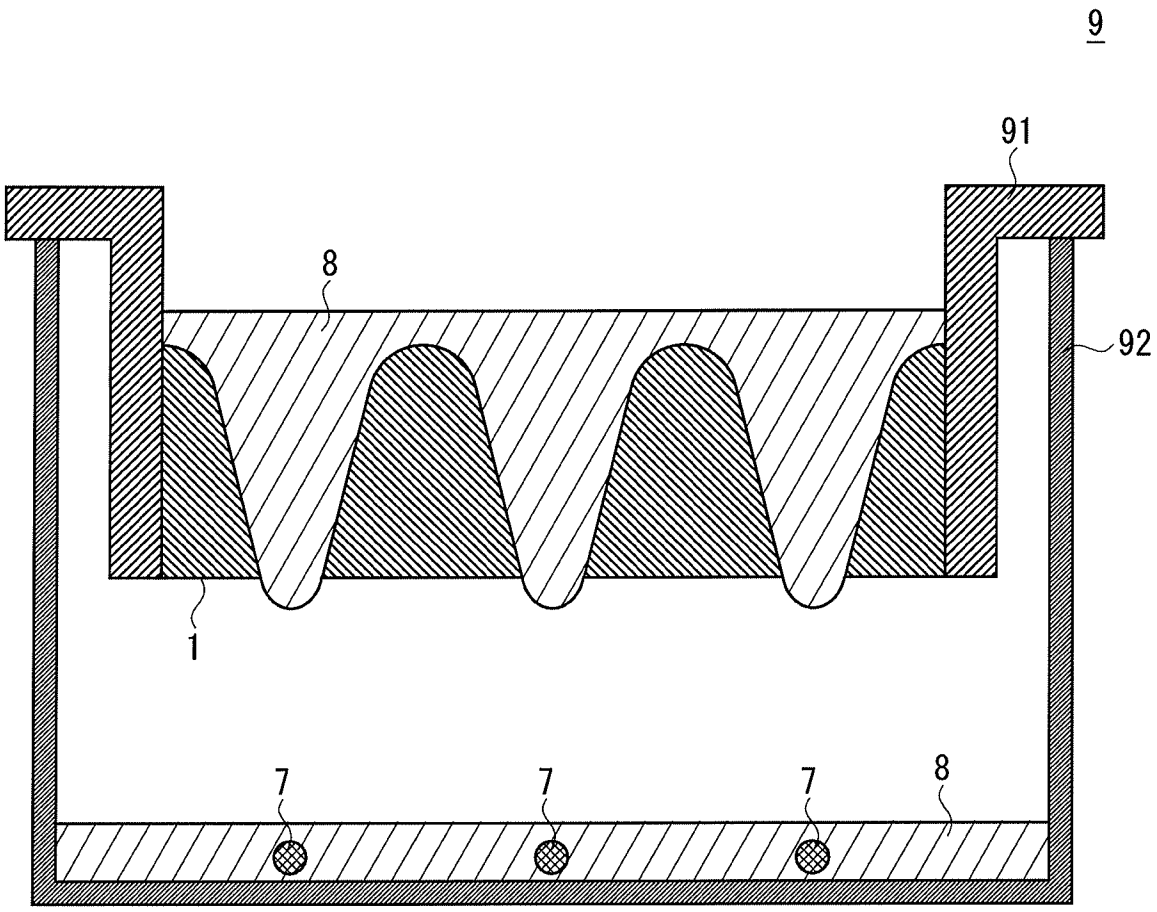


Fig. 15

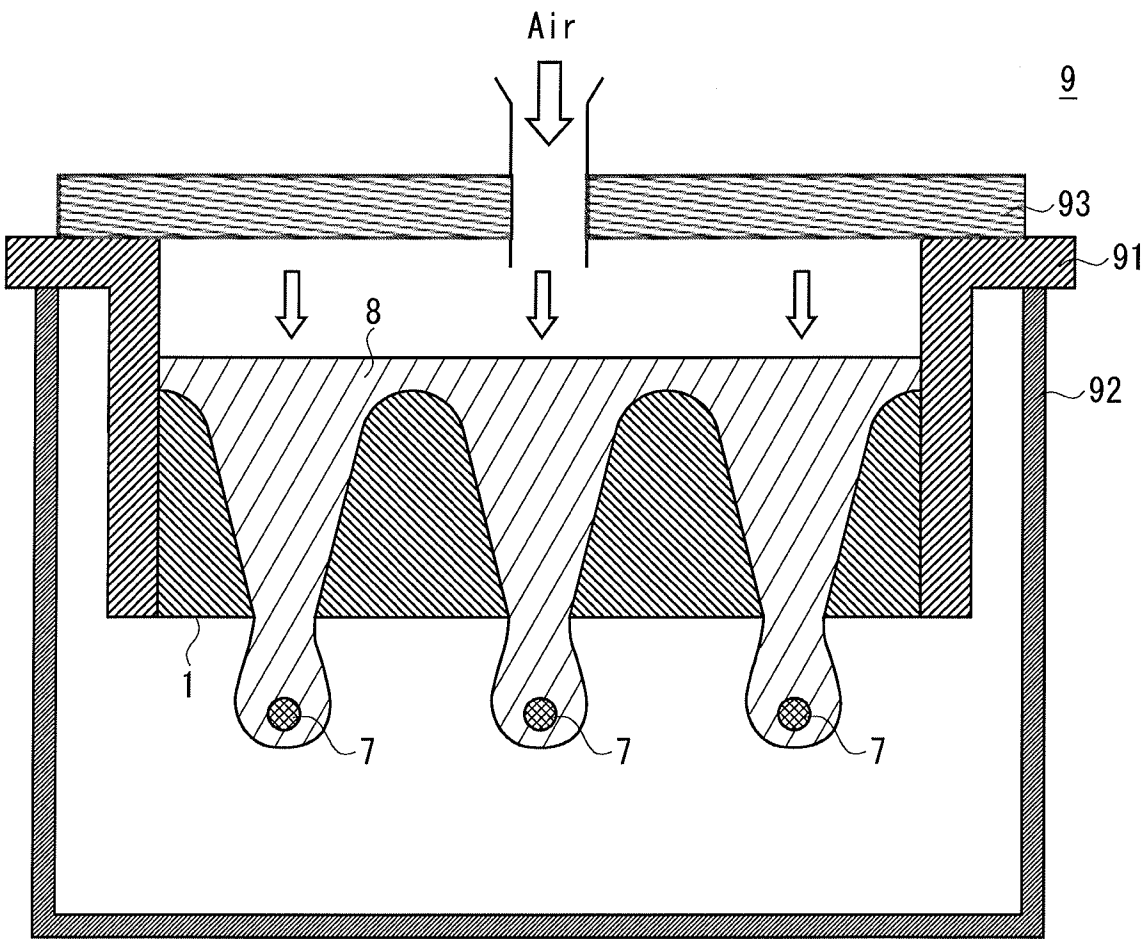


Fig. 16

Fig. 17

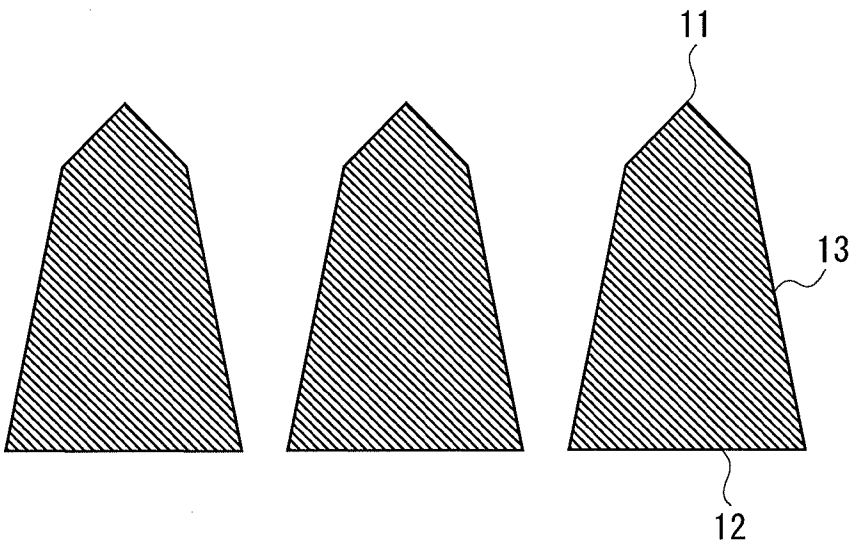


Fig. 18

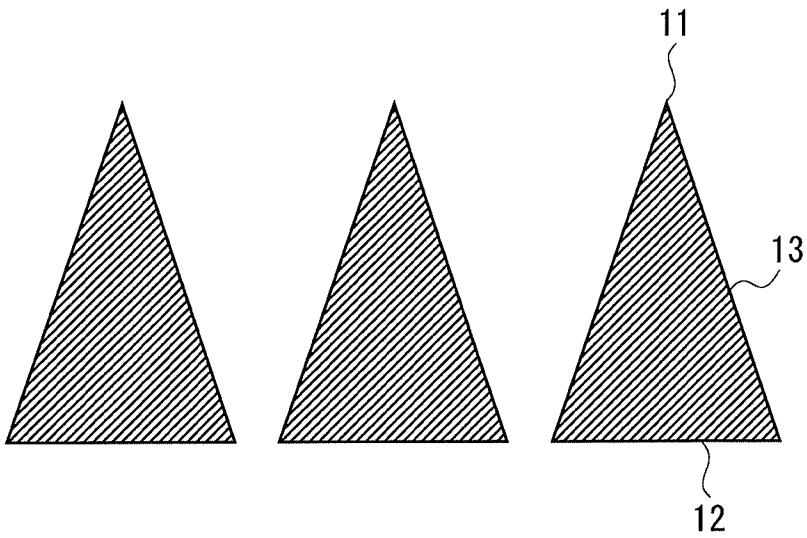


Fig. 19

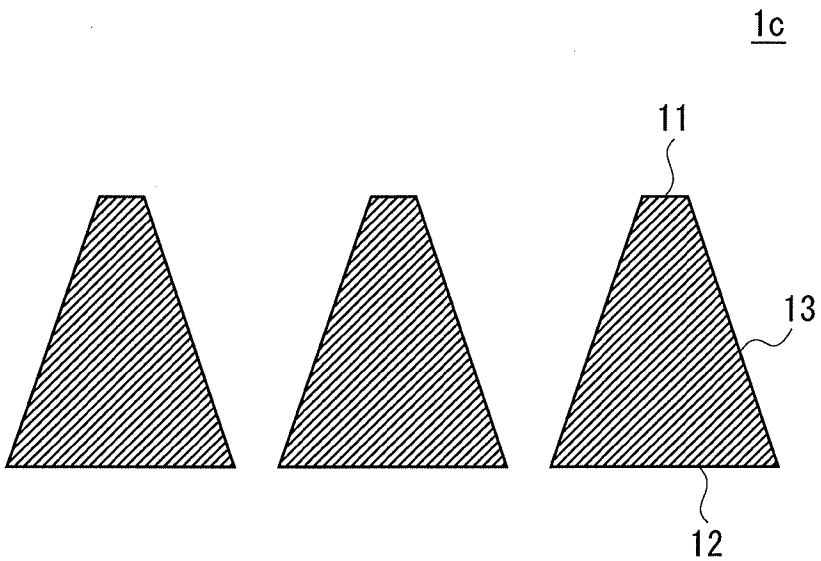


Fig. 20

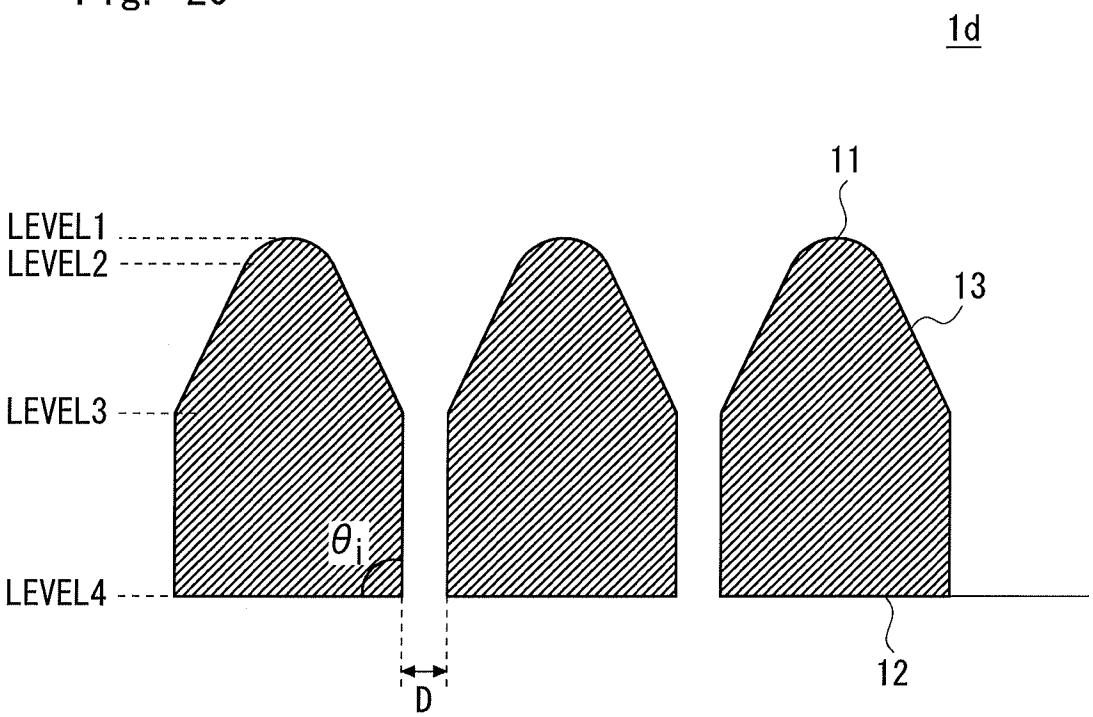


Fig. 21

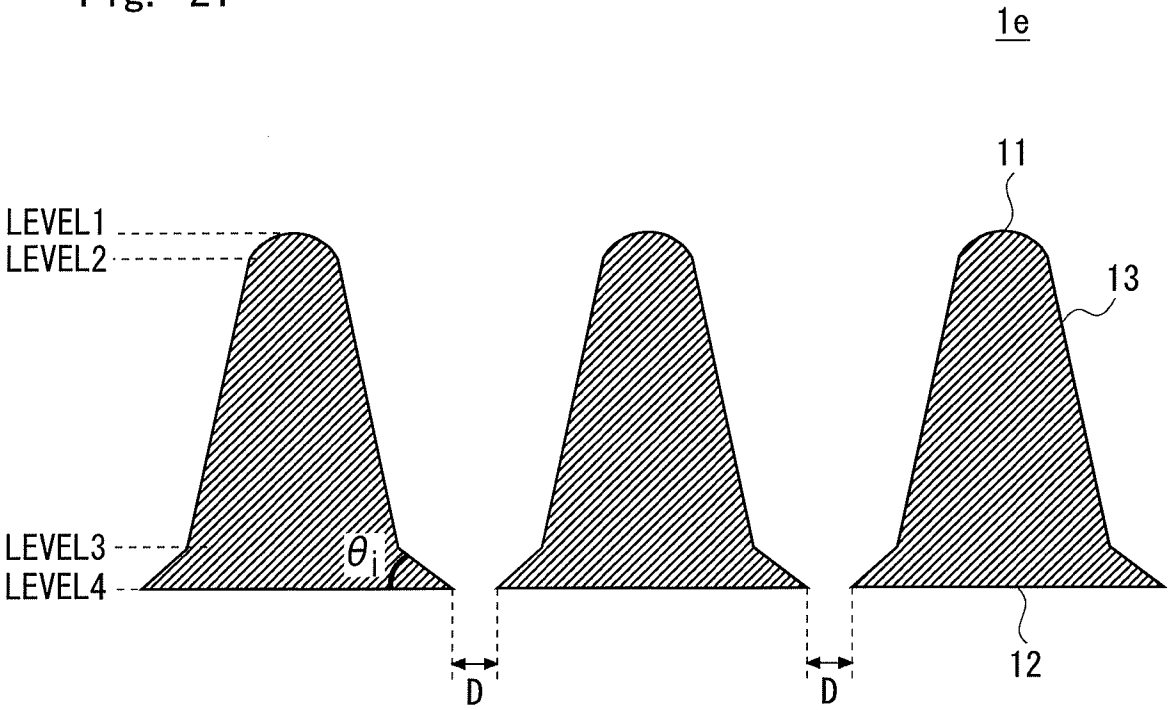

1e
11
LEVEL1
LEVEL2
13
LEVEL3
LEVEL4
θi
D
D
12

Fig. 22

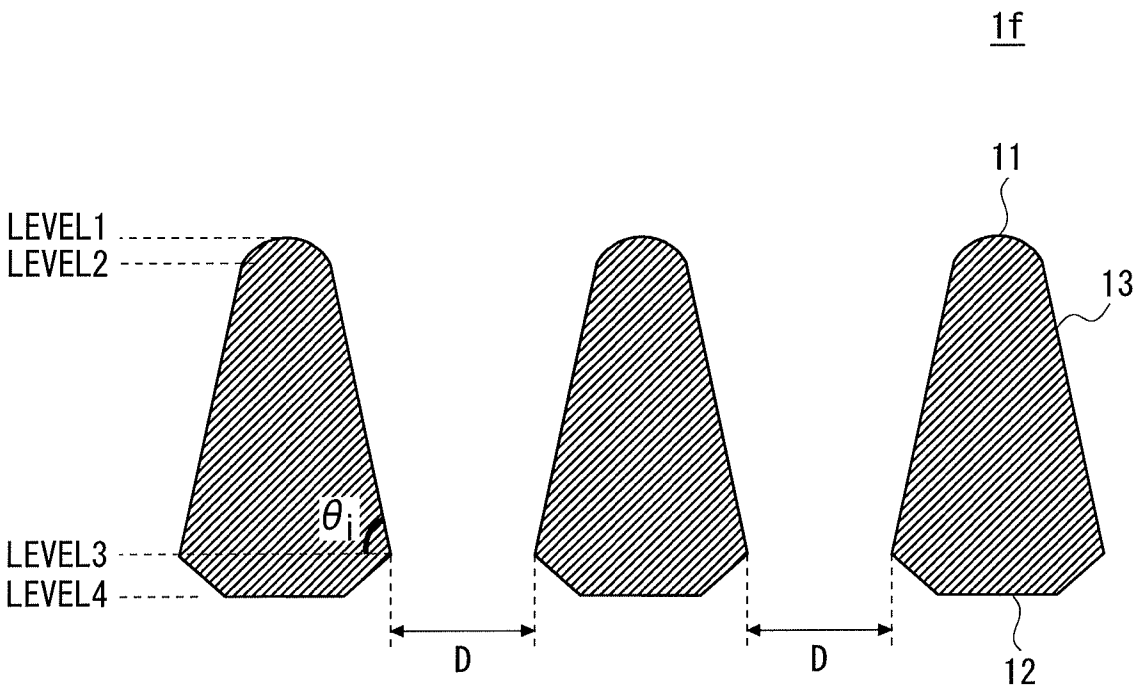

1f
11
LEVEL1
LEVEL2
13
θi
LEVEL3
LEVEL4
D
D
12

Fig. 23

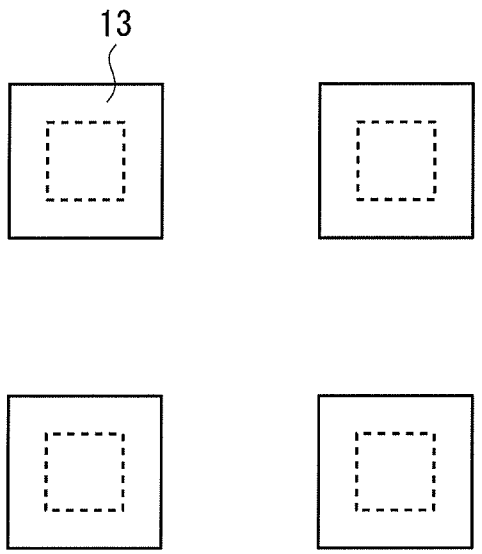


Fig. 24

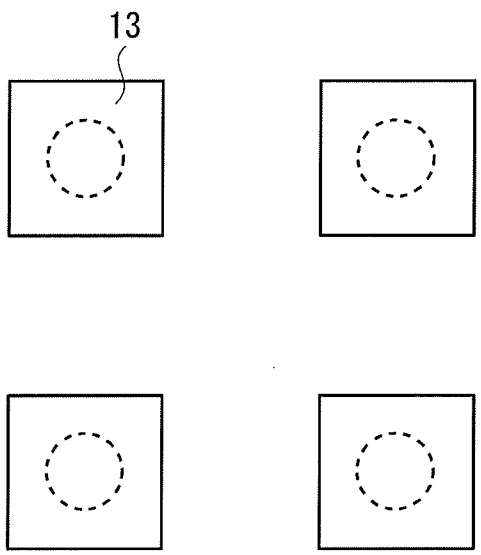


Fig. 25

1i

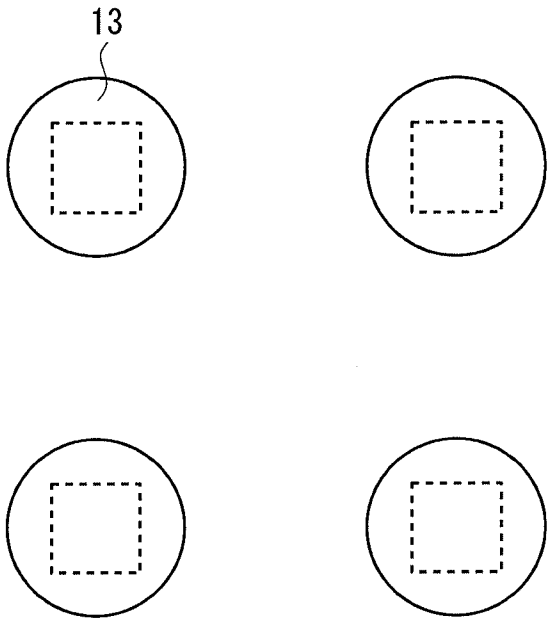
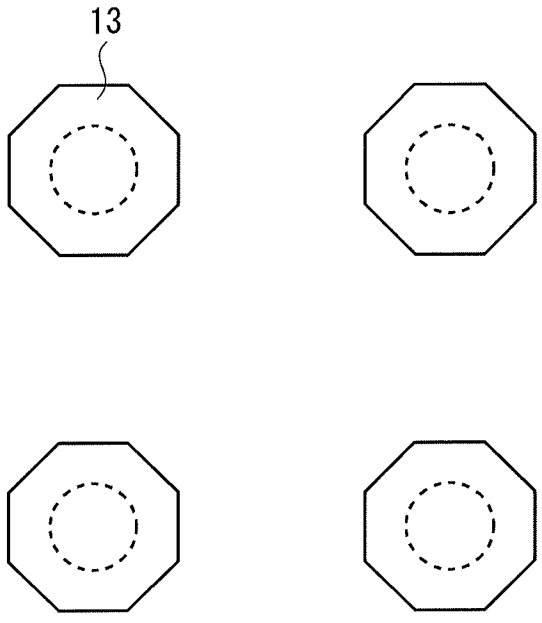


Fig. 26

1j



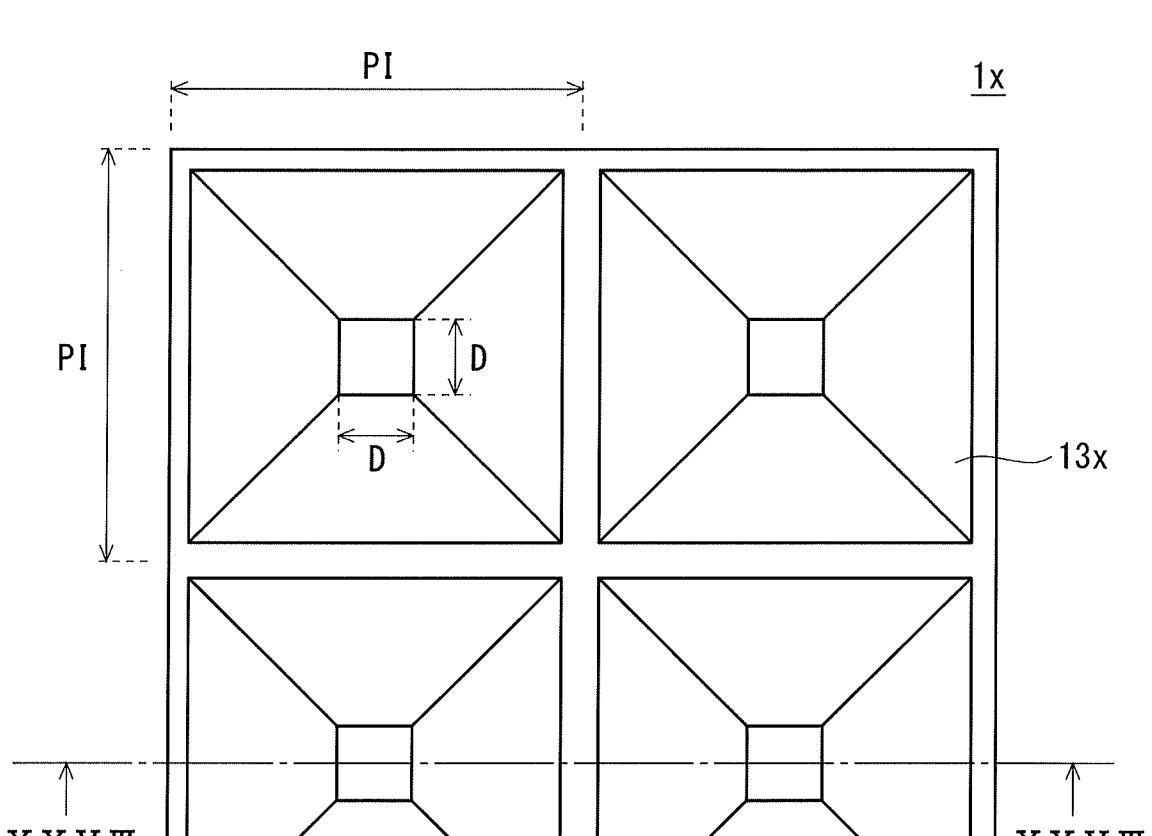


Fig. 27

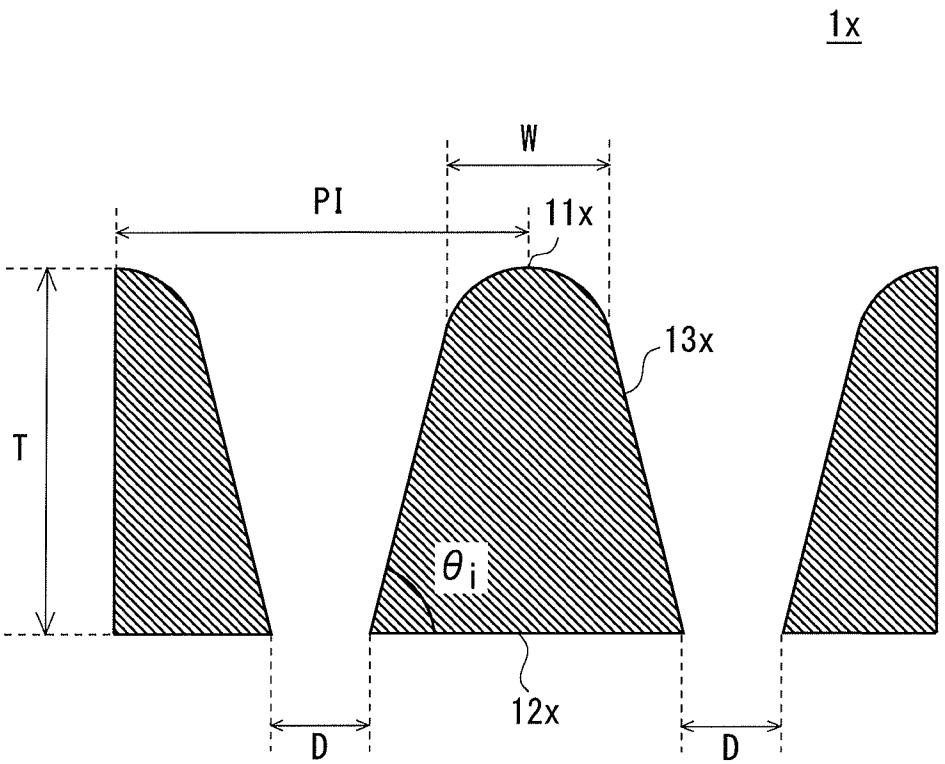


Fig. 28

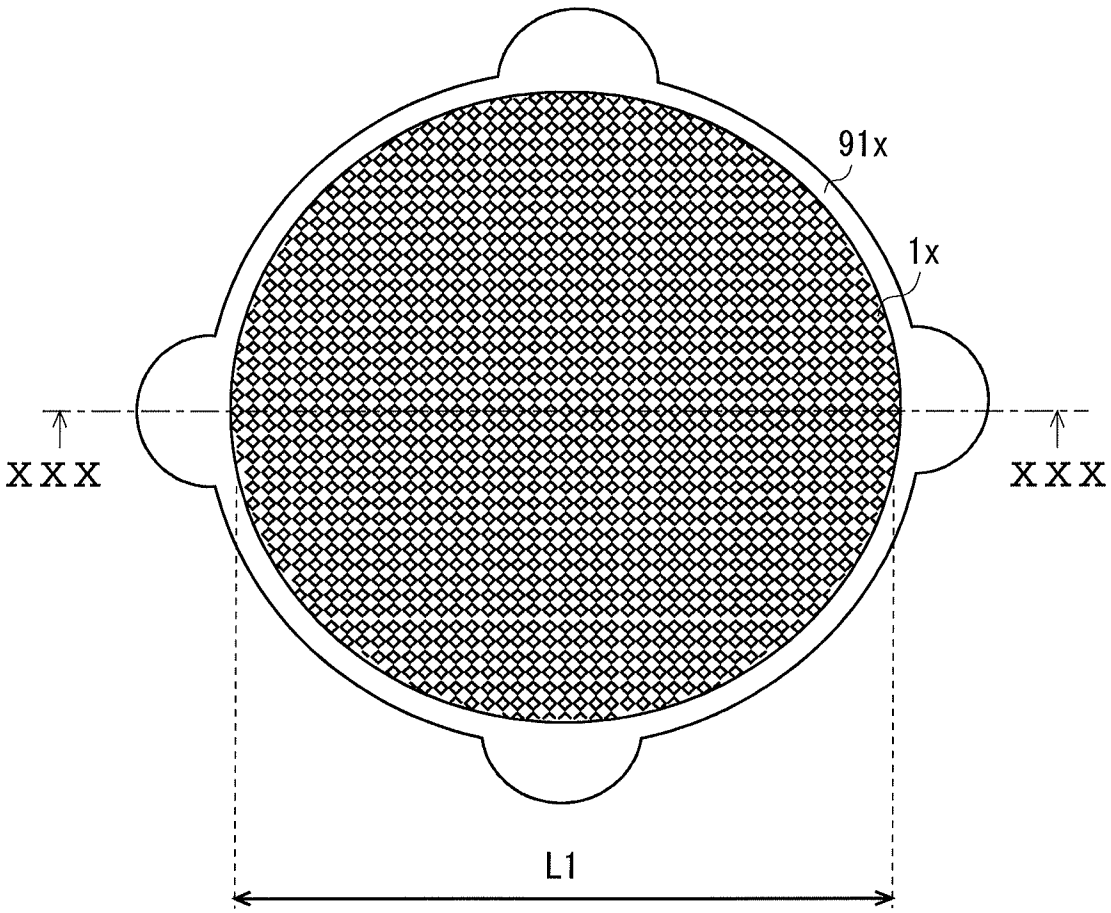


Fig. 29

Fig. 30

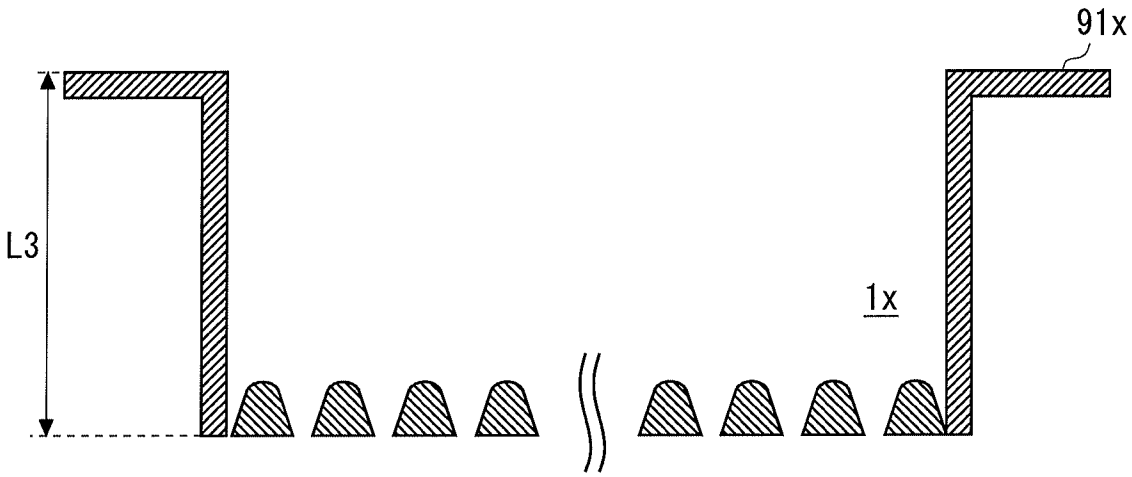
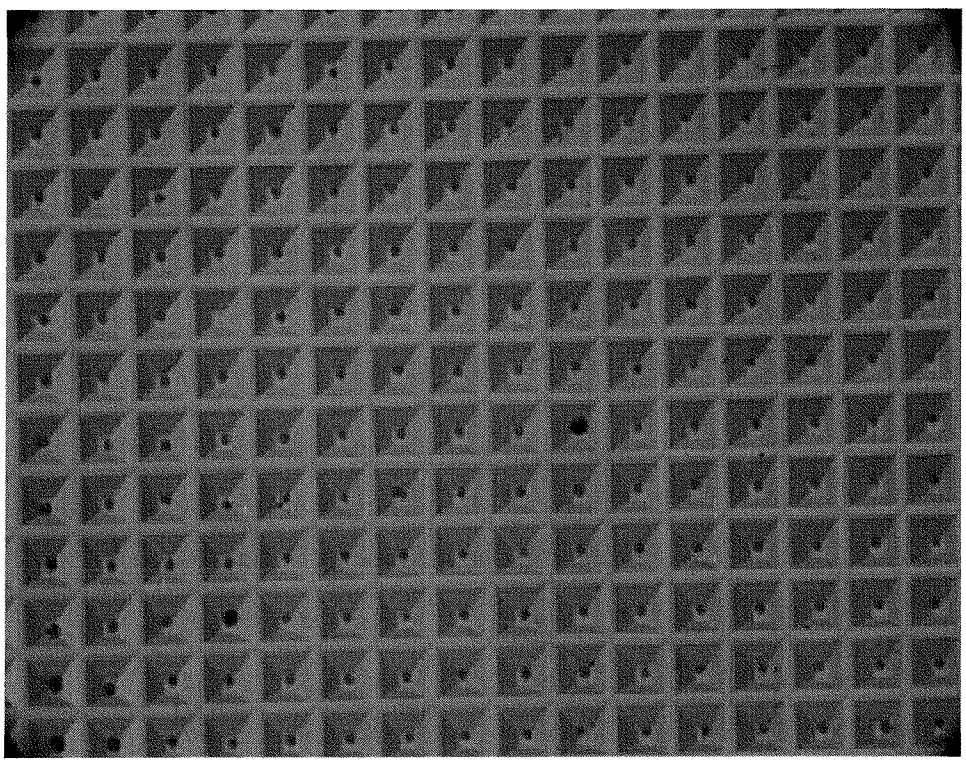
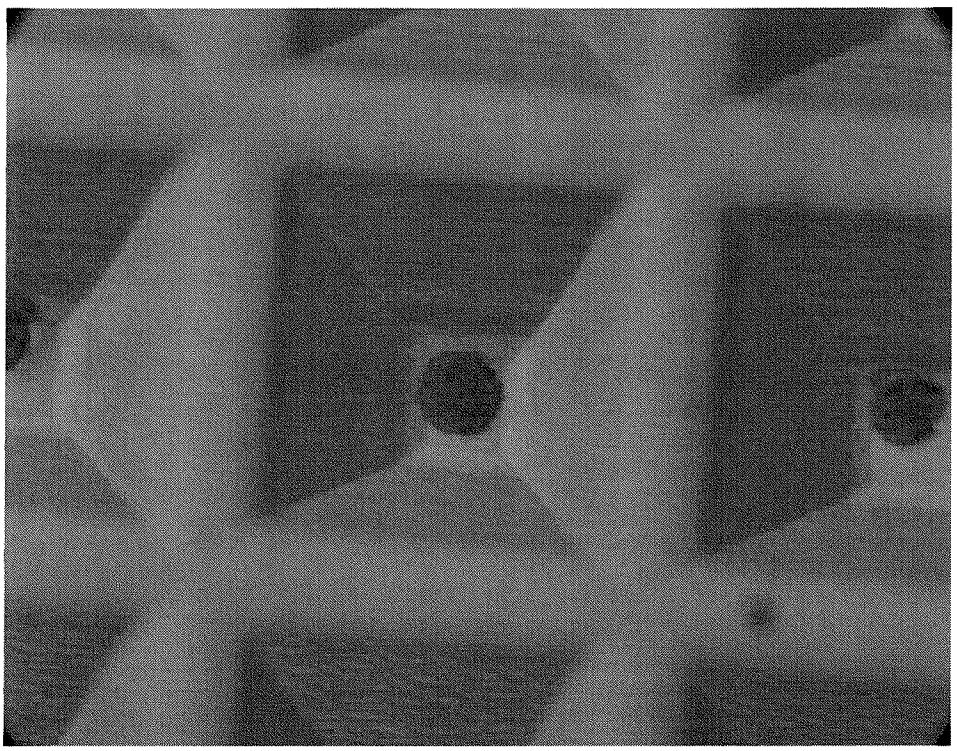


Fig. 31



×7.5



×75

Fig. 32

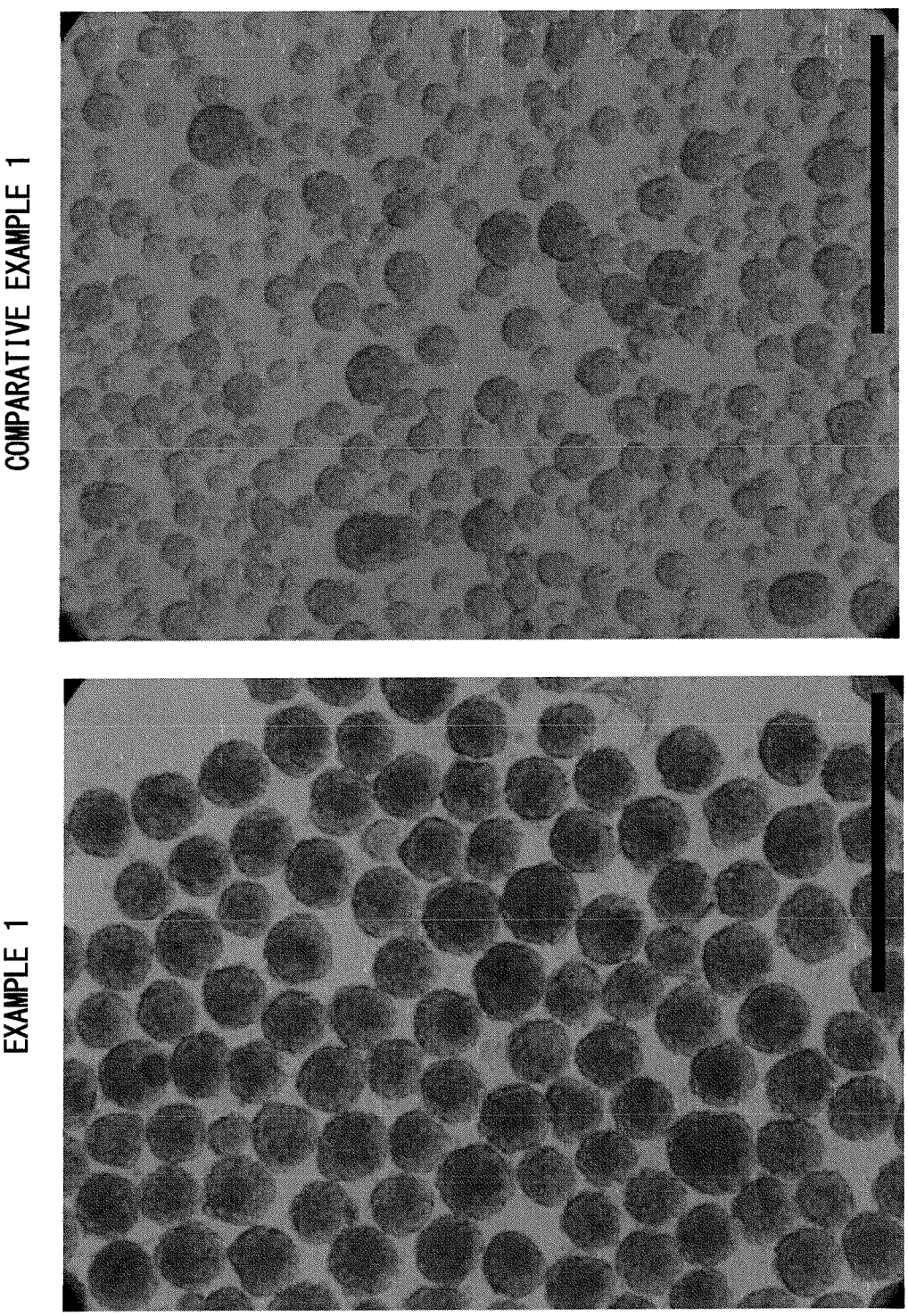
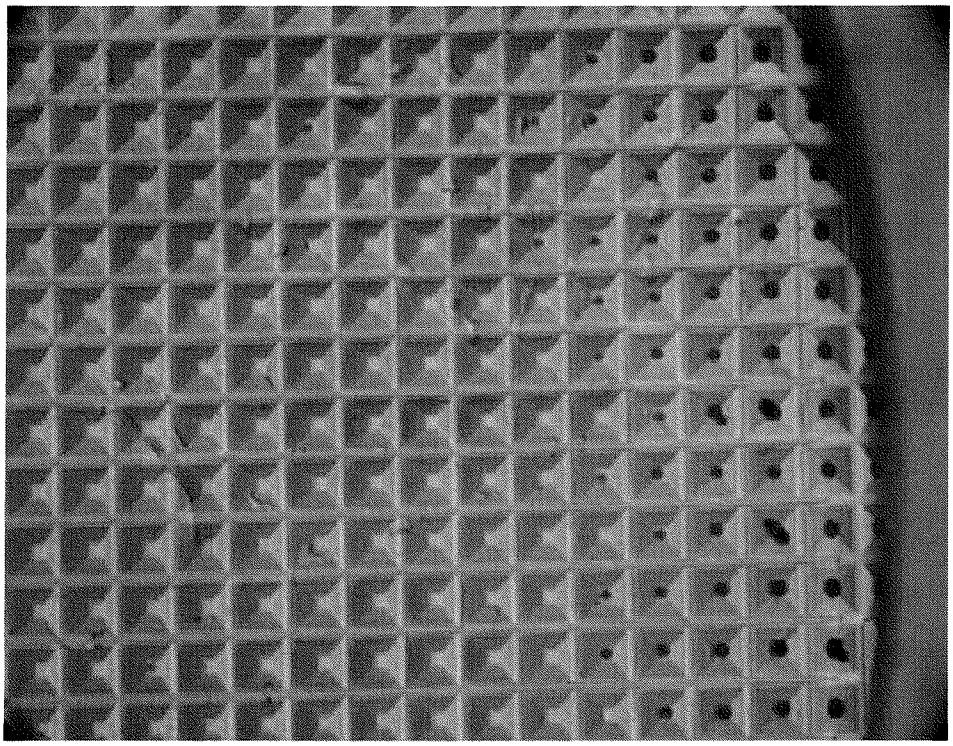


Fig. 33

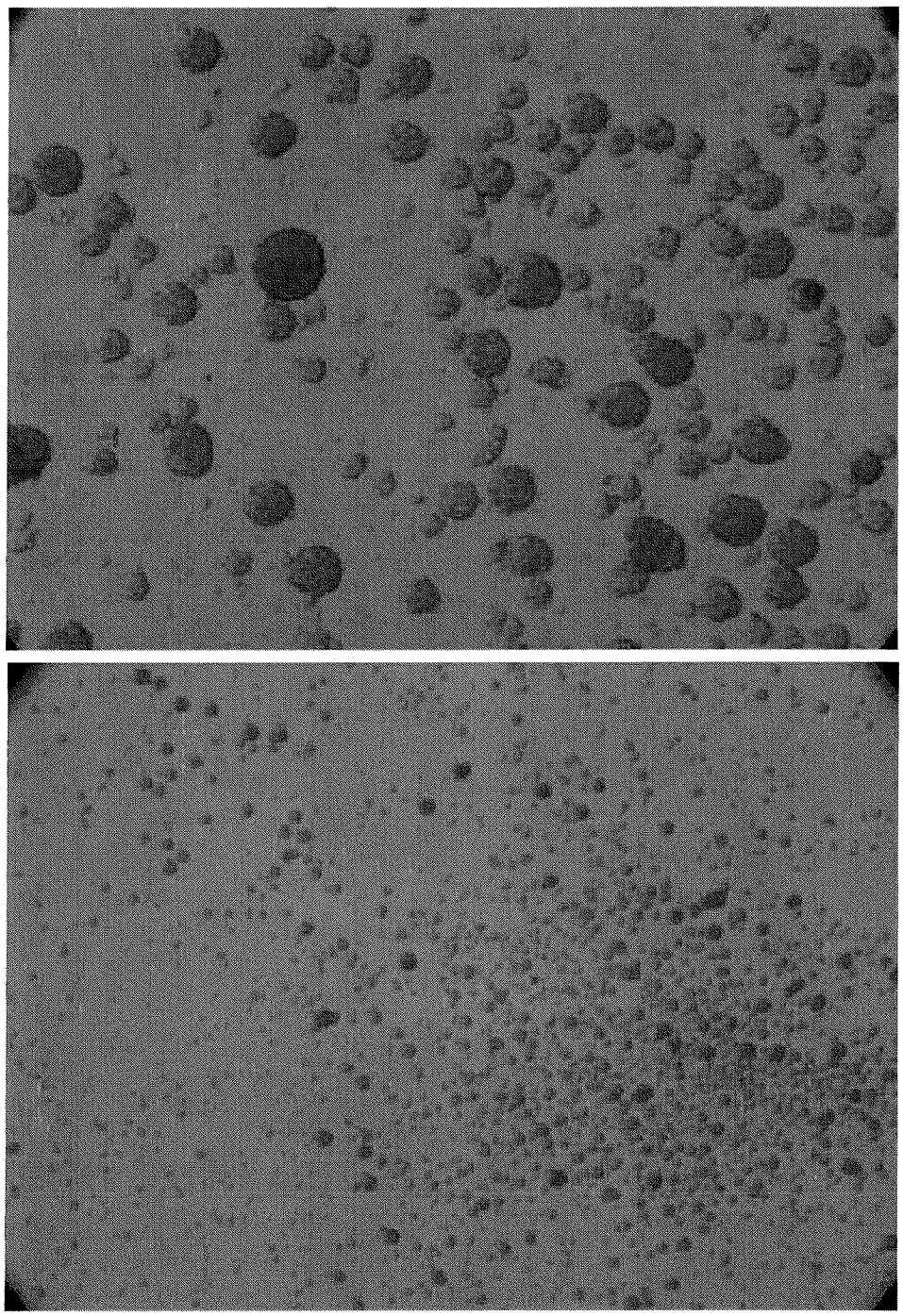


×10

Fig. 34

Fig. 35

FLOATING AULTURE ON SILICON SURFACE(CONTROL)



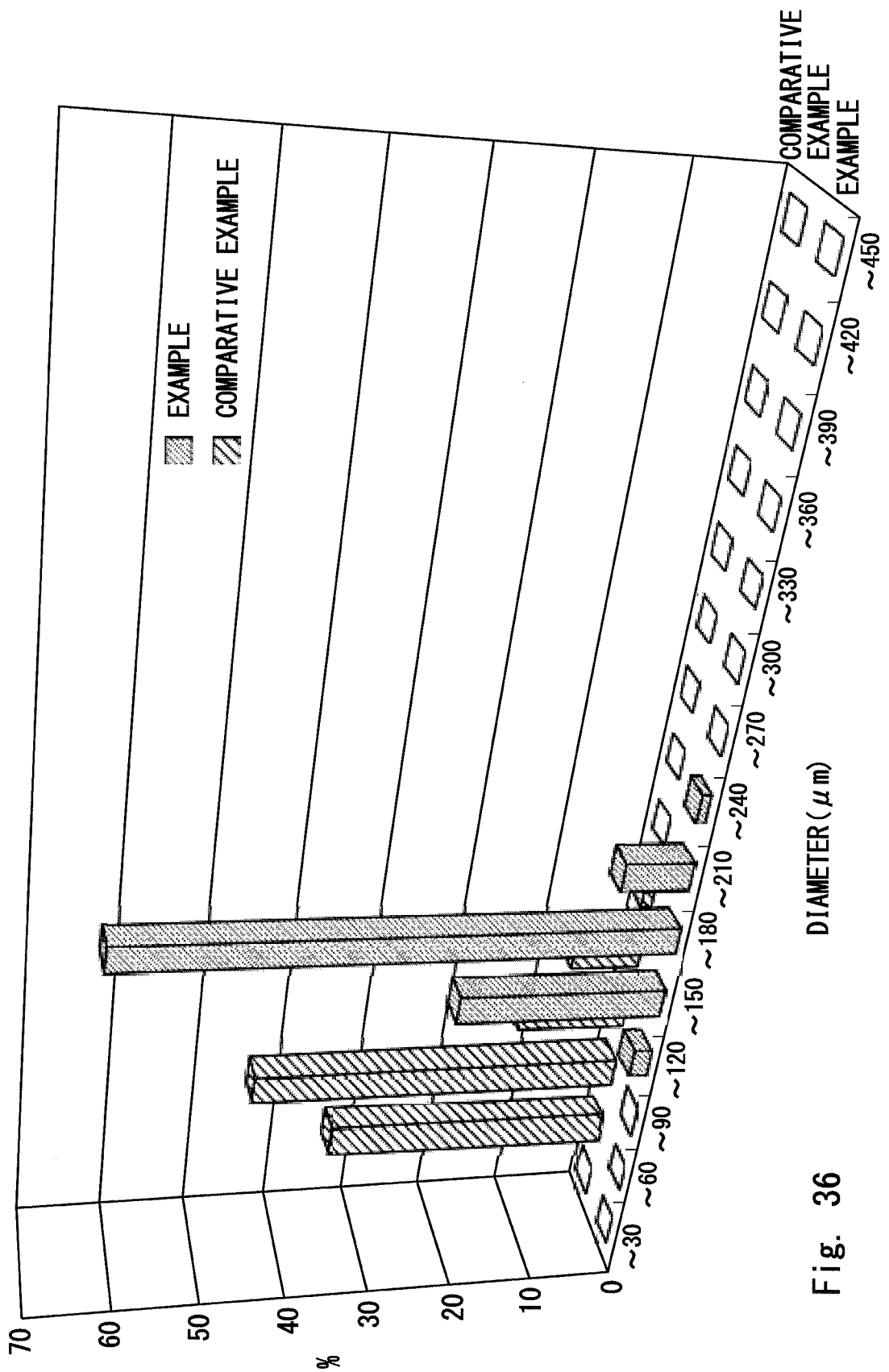

EXAMPLE
COMPARATIVE EXAMPLE
%
70
60
50
40
30
20
10
0
~30
~60
~90
~120
~150
~180
~210
~240
~270
~300
~330
~360
~390
~420
~450
DIAMETER(μm)
EXAMPLE
COMPARATIVE EXAMPLE

Fig. 36

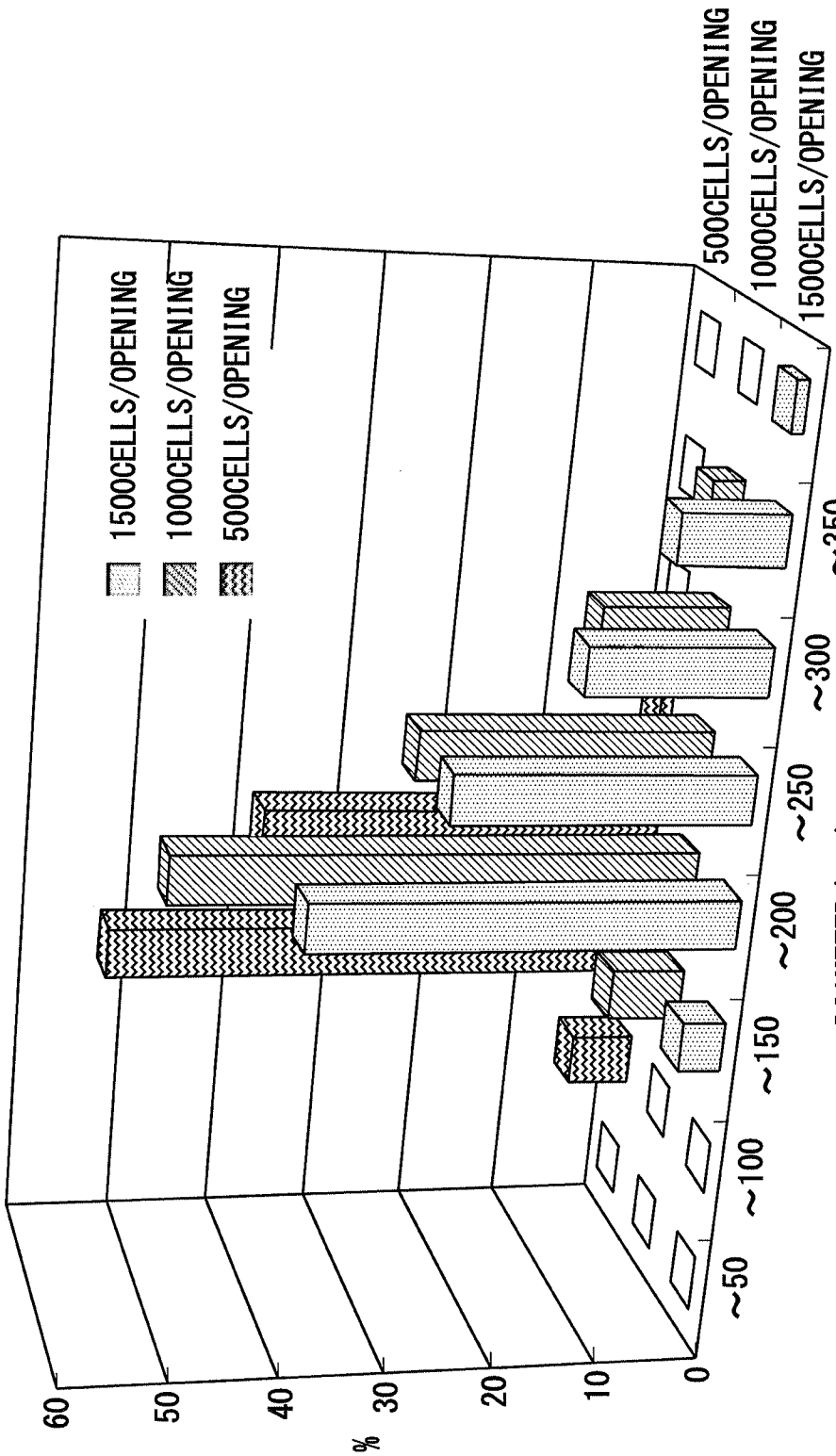

1500CELLS/OPENING
1000CELLS/OPENING
500CELLS/OPENING
60
50
40
30
20
10
0
%
~50
~100
~150
~200
~250
~300
~350
~400
DIAMETER(μm)
500CELLS/OPENING
1000CELLS/OPENING
1500CELLS/OPENING

Fig. 37